



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: **Confirmation No. 1393**

Takashi TANAKA ET AL.

: Docket No. 2001_1507A

Serial No. 09/970,621

: Group Art Unit 3723

Filed October 5, 2001

: Examiner Lee D. Wilson

METHOD FOR SUPPLYING SLURRY
TO POLISHING APPARATUS

EW
11-4-03
#6
Election

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

This is in response to the Restriction Requirement of October 3, 2003.

Applicants, by their undersigned representative, hereby elect the invention of Group I, i.e. claims 12-21 and 23-30. However, since the subject of the Group II claims has already been considered by the Examiner, it is respectfully submitted that there would be no undue burden on the Examiner to examine the Group II claims along with the Group I claims. Accordingly, it is respectfully requested that the Examiner withdraw the restriction requirement and examine all of the currently pending claims together.

Having made the required election, a full examination on the merits of the elected invention is hereby requested.

Respectfully submitted,

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OCT 30 2003

TECHNOLOGY CENTER R3700

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